



PTO/SB/08

Submitted: September 23, 2004

Substitute for form 1449/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT				<i>Complete if Known</i>	
				Application Number	10/057,037
				Filing Date	1/24/02
				First Named Inventor	Laxman MURUGESH et al.
				Group Art Unit	1746
				Examiner	Markoff, A.
Sheet	1	of	2	Attorney Docket	006383

U.S. PATENT DOCUMENTS						
Examiner Initials	Cite No.	U.S. Patent Document		Date of Publication	Name of Patentee or Applicant	Pages, Columns, Lines Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code			
AM		4,289,188		Sep. 1981	Mizutani et al.	
		4,430,151		Feb. 1984	Tsukada	
		4,491,499		Jan. 1985	Jerde et al.	
		5,308,414		May. 1994	O'Neill et al.	
		5,320,704		Jun. 1994	Horioka et al.	
		5,348,614		Sep. 1994	Jerbic	
		5,356,478		Oct. 1994	Chen et al.	
		5,552,016		Sep. 1996	Ghanayem.	
		5,565,114		Oct. 1996	Saito et al.	
		5,632,821		May. 1997	Doi	
		5,812,403		Sep. 1998	Fong et al.	
AN		6,534,007	B1	Mar. 2003	Blonigan et al.	

Examiner Signature	A. MARKOFF	Date Considered	11/22/04
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		Country Code	Number	Kind Code				
AM		WO	99/06610	A1	Feb. 1999	Blonigan et al.		

OTHER PRIOR ART — NON PATENT LITERATURE DOCUMENTS				
Examiner Initials	Cite No.	Author (in capital letters); title of article; title of book, journal, symposium, catalog, etc.; date; pages; volume/issue no.; publisher; city and/or country where published.		T
DM		TODA, "Thin beam bulk micromachining based on RIE and xenon difluoride silicon etching," IEEE Transducers '97, International Conference on Solid-State Sensors and Actuators, pages 671-674, Chicago, 1997.		

Examiner Signature	A. MARKOFF	Date Considered	11/22/04
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